

Search Terms	
1	BEST
2	BESTS
3	CALIBRATED
4	CALIBRATING
5	CALIBRATION
6	CALIBRATIONS
7	CORRECTED
8	CORRECTING
9	CORRECTINGS
10	CORRECTION
11	CORRECTIONS
12	EDGE
13	EDGES
14	EDGEWIDTH
15	EDGEWIDTHS
16	ERROR
17	ERRORS
18	EXPOSURE
19	EXPOSURES
20	FOCU
21	FOCUS
22	LITHOGRAPHIC
23	LITHOGRAPHICS
24	LITHOGRAPHIES
25	LITHOGRAPHY
26	LITHOGRAPHYS
27	OPTIMUM
28	OPTIMUMS
29	PHOTOLITHOGRAPHIC
30	PHOTOLITHOGRAPHICS
31	PHOTOLITHOGRAPHIES
32	PHOTOLITHOGRAPHY
33	PHOTOLITHOGRAPHYS
34	RESIST
35	RESISTS
36	WAFER
37	WAFERS
38	WIDTH

	Total	USPAT	US-PGPUB	EPO	JPO	Derwent	IBM TDB	USOCR
1	934561							
2	153							
3	110252							
4	43934							
5	144317							
6	8187							
7	289539							
8	245898							
9	5							
10	430844							
11	48632							
12	1783710							
13	986829							
14	14							
15	1							
16	664064							
17	284255							
18	525850							
19	27701							
20	65							
21	243173							
22	45193							
23	36							
24	225							
25	49116							
26	1							
27	555625							
28	479							
29	42108							
30	7							
31	16							
32	59910							
33	1							
34	296997							
35	72739							
36	302921							
37	98157							
38	1409611							

Search Terms	
39	WIDTHS
40	CALIBRATIONS
41	((((PHOTOLITHOGRAPHIC OR PHOTOLITHOGRAPHY OR LITHOGRAPHY OR LITHOGRAPHIC) AND (FOCUS SAME (EDGEWIDTH OR WIDTH OR EDGE)) AND FOCUS) AND ((FOCUS SAME (OPTIMUM OR BEST)) SAME (CALIBRATING OR CALIBRATED OR CORRECTING OR CORRECTED OR CALIBRATION OR CORRECTION OR ERROR)) AND RESIST AND EXPOSURE AND WAFER)

	Total	USPAT	US-PGPUB	EPO	JPO	Derwent	IBM TDB	USOCR
39	154100							
40	1							
	108	75	33	0	0	0	0	
41								

	U	1	Document ID	Issue Date	Pages	Title	Current OR
1	<input type="checkbox"/>	<input type="checkbox"/>	US 20030197130 A1	20031023	38	Convergent charged particle beam apparatus and inspection method using same	250/491.1
2	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030158710 A1	20030821	26	Contact hole profile and line edge width metrology for critical image control and feedback of lithographic focus	702/189
3	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030142282 A1	20030731	15	Pattern forming method	355/55
4	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030139833 A1	20030724	17	Methods and apparatus for determining optimum exposure threshold for a given photolithographic model	700/97
5	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030121022 A1	20030626	27	Method and its apparatus for manufacturing semiconductor device	716/21
6	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030103196 A1	20030605	29	Exposure method and exposure apparatus	355/55
7	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030095267 A1	20030522	38	Focus masking structures, focus patterns and measurements thereof	356/614
8	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030064298 A1	20030403	33	Optical proximity correction method utilizing phase-edges as sub-resolution assist features	430/5
9	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030048458 A1	20030313	32	Method for determining lithographic focus and exposure	356/601
10	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030036006 A1	20030220	10	Methods for monitoring photoresists	430/30
11	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030031943 A1	20030213	18	Focus monitoring method, focus monitoring system, and device fabricating method	430/30
12	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20030015660 A1	20030123	74	Method and system for monitoring a semiconductor device manufacturing process	250/311
13	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020191165 A1	20021219	12	Lithographic apparatus, device manufacturing method, and device manufactured thereby	355/52
14	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020182521 A1	20021205	41	Method of manufacturing semiconductor device	430/22

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
1	250/310; 250/397; 250/398; 250/492.2		Tanaka, Maki et al.	<input checked="" type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030197130	<input type="checkbox"/>
2			Bowley, Reginald R. JR. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030158710	<input type="checkbox"/>
3	355/52; 355/53; 355/77		Fujimoto, Masashi	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030142282	<input type="checkbox"/>
4	257/E21.525; 700/121; 716/19		Pierrat, Christophe et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030139833	<input type="checkbox"/>
5			Yoshitake, Yasuhiro et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030121022	<input type="checkbox"/>
6	250/548; 355/53; 355/77; 356/399; 356/400		Hirukawa, Shigeru	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030103196	<input type="checkbox"/>
7			Mieher, Walter Dean et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030095267	<input type="checkbox"/>
8	430/296; 430/322; 716/19; 716/21		Broeke, Douglas Van Den et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030064298	<input type="checkbox"/>
9			Mieher, Walter et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030048458	<input type="checkbox"/>
10			Feké, Gilbert D. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030036006	<input type="checkbox"/>
11	355/18		Nakao, Shuji et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030031943	<input type="checkbox"/>
12			Shishido, Chie et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20030015660	<input type="checkbox"/>
13	355/53; 355/55; 355/67; 355/77; 356/399		Baselmans, Johannes J.M. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020191165	<input type="checkbox"/>
14	430/30; 430/330		Fujisawa, Tadahito et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020182521	<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR
15	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020172876 A1	20021121	12	Method of calibration of a lithographic apparatus, mask for use in calibration of lithographic apparatus, lithographic apparatus, device manufacturing method, device manufactured thereby	430/22
16	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020167651 A1	20021114	14	Lithographic apparatus, device manufacturing method, and device manufactured thereby	355/67
17	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020159040 A1	20021031	49	Specification determining method, projection optical system making method and adjusting method, exposure apparatus and making method thereof, and computer system	355/52
18	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020158185 A1	20021031	14	Method and system for improving focus accuracy in a lithography system	250/201.2
19	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020152452 A1	20021017	27	Illumination optimization for specific mask patterns	716/21
20	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020097386 A1	20020725	37	Detection apparatus and exposure apparatus using the same	355/67
21	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020053643 A1	20020509	38	Convergent charged particle beam apparatus and inspection method using same	250/491.1
22	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020048006 A1	20020425	35	Scan type projection exposure apparatus and device manufacturing method using the same	355/53
23	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020041377 A1	20020411	76	Aerial image measurement method and unit, optical properties measurement method and unit, adjustment method of projection optical system, exposure method and apparatus, making method of exposure apparatus, and device manufacturing method	356/399
24	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020036762 A1	20020328	53	Projection exposure method and apparatus	355/53

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
15	355/18; 430/30		Baselmans, Johannes Jacobus Matheus	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020172876	<input type="checkbox"/>
16	355/53; 356/399; 356/400		Boonman, Marcus Emile Joannes et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020167651	<input type="checkbox"/>
17	355/53; 355/55; 355/67; 355/77; 356/399; 356/400; 356/401		Hamatani, Masato et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020159040	<input type="checkbox"/>
18			Nelson, Michael L. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020158185	<input type="checkbox"/>
19	716/19; 716/20		Socha, Robert John	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020152452	<input type="checkbox"/>
20	355/53; 355/68; 356/399; 356/400		Mishima, Kazuhiko	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020097386	<input type="checkbox"/>
21	250/492.2		Tanaka, Maki et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020053643	<input type="checkbox"/>
22	355/52; 355/55; 355/67; 355/77		Mishima, Kazuhiko	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020048006	<input type="checkbox"/>
23			Hagiwara, Tsuneyuki et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020041377	<input type="checkbox"/>
24	355/55; 355/67; 355/72; 355/75; 355/76; 355/77		Nishi, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020036762	<input type="checkbox"/>



	U	1	Document ID	Issue Date	Pages	Title	Current OR
25	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020036758 A1	20020328	14	Method of operating an optical imaging system, lithographic projection apparatus, device manufacturing method, and device manufactured thereby	355/53
26	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020021460 A1	20020221	55	System and method for characterizing optical systems using holographic reticles	359/1
27	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020018217 A1	20020214	13	Optical critical dimension metrology system integrated into semiconductor wafer process tool	356/601
28	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020008869 A1	20020124		Method of measuring aberration in an optical imaging system	356/124
29	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020008863 A1	20020124		Projection exposure apparatus	355/55
30	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20020003216 A1	20020110		Exposure apparatus, surface position adjustment unit, mask, and device manufacturing method	250/548
31	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20010036604 A1	20011101		Multiple exposure method	430/394
32	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20010029403 A1	20011011		Method and apparatus for determining optimum exposure threshold for a given photolithographic model	700/121
33	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 20010012098 A1	20010809		SCAN TYPE PROJECTION EXPOSURE APPARATUS AND DEVICE MANUFACTURING METHOD USING THE SAME	355/53
34	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6614503 B1	20030902		Projection exposure apparatus, and device manufacturing method which compensate for a change in optical performance of a projection optical system	355/30
35	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6602728 B1	20030805		Method for generating a proximity model based on proximity rules	438/16
36	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6590636 B2	20030708		Projection exposure method and apparatus	355/53
37	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6581023 B1	20030617		Accurate contact critical dimension measurement using variable threshold method	702/155
38	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6563564 B2	20030513		Method of operating an optical imaging system, lithographic projection apparatus, device manufacturing method, and device manufactured thereby	355/52

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
25	430/30; 430/312		de Mol, Christianus Gerardus Maria et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020036758	<input type="checkbox"/>
26			Hansen, Matthew E.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020021460	<input type="checkbox"/>
27			Weber-Grabau, Michael et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	US 20020018217	<input type="checkbox"/>
28			Van der Laan, Hans et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
29	355/30; 355/53; 355/67; 355/77		Taniguchi, Tetsuo et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
30			Kida, Yoshiki et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
31	430/322; 430/396		Kawashima, Miyoko	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
32	700/29		Pierrat, Christophe et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
33			MISHIMA, KAZUHIKO	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
34	355/52; 355/53; 355/55; 430/30		Uzawa, Shigeyuki	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
35	438/14; 716/19; 716/20; 716/21; 716/5; 716/6		Liebmann, Lars W. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
36	355/75; 355/77		Nishi, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
37	382/145; 702/150		Kim, Hung-Eil	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
38	355/55		de Mol, Christianus Gerardus Maria et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR
39	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6559459 B2	20030506		Convergent charged particle beam apparatus and inspection method using same	250/491.1
40	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS RE38085 E	20030422		Exposure method and projection exposure apparatus	355/53
41	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS RE38038 E	20030318		Exposure method and projection exposure apparatus	355/53
42	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6519501 B2	20030211		Method of determining optimum exposure threshold for a given photolithographic model	700/121
43	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS RE37946 E	20021231		Exposure method and projection exposure apparatus	355/53
44	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6493063 B1	20021210		Critical dimension control improvement method for step and scan photolithography	355/53
45	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS RE37913 E	20021126		Exposure method and projection exposure apparatus	355/53
46	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6486953 B1	20021126		Accurate real-time landing angle and telecentricity measurement in lithographic systems	356/400
47	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6440616 B1	20020827		Mask and method for focus monitoring	430/5
48	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6425117 B1	20020723		System and method for performing optical proximity correction on the interface between optical proximity corrected cells	716/21
49	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6376139 B1	20020423		Control method for exposure apparatus and control method for semiconductor manufacturing apparatus	430/30
50	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6335784 B1	20020101		Scan type projection exposure apparatus and device manufacturing method using the same	355/53
51	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6335532 B1	20020101		Convergent charged particle beam apparatus and inspection method using same	250/491.1
52	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6327022 B1	20011204		Projection exposure method and apparatus	355/53
53	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6317211 B1	20011113		Optical metrology tool and method of using same	356/401
54	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6304317 B1	20011016		Projection apparatus and method	355/55
55	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS RE37391 E	20010925		Exposure method and projection exposure apparatus	355/53
56	<input checked="" type="checkbox"/>	<input type="checkbox"/>	IUS 6258489 B1	20010710		Mask design utilizing dummy features	430/5

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
39	250/310; 250/397; 250/398; 250/492.2		Tanaka, Maki et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
40	355/55		Nishi, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
41	355/55		Nishi, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
42			Pierrat, Christophe et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
43	355/55		Nishi, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
44	355/77		Selmann, Rolf et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
45	355/55		Nishi, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
46			Gordon, Michael S. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
47	430/22		Izuha, Kyoko et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
48	430/5; 716/19; 716/20		Pasch, Nicholas F. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
49	430/311		Fujisawa, Tadahito et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
50	355/55; 430/30		Mishima, Kazuhiko	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
51	250/310; 250/397; 250/398; 250/492.2		Tanaka, Maki et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
52	355/54; 355/75		Nishi, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
53	356/400		Ausschnitt, Christopher P. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
54	355/53; 355/67; 355/71		Taniguchi, Tetsuo et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
55	355/55		Nishi, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
56			Stanton, William et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR
57	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6221539 B1	20010424		Mask pattern correction method and a recording medium which records a mask pattern correction program	430/5
58	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6208469 B1	20010327		Method of adjusting reduction projection exposure device	359/637
59	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6191429 B1	20010220		Projection exposure apparatus and method with workpiece area detection	250/548
60	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6178360 B1	20010123		Methods and apparatus for determining optimum exposure threshold for a given photolithographic model	700/121
61	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6130750 A	20001010		Optical metrology tool and method of using same	356/401
62	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6118516 A	20000912		Projection exposure apparatus having a filter arranged in its projection optical system and method for protecting circuit patterns	355/53
63	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6090510 A	20000718		Method for scanning exposure	430/30
64	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6078380 A	20000620		Projection exposure apparatus and method involving variation and correction of light intensity distributions, detection and control of imaging characteristics, and control of exposure	355/52
65	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6051349 A	20000418		Apparatus for coating resist and developing the coated resist	430/30
66	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6040909 A	20000321		Surface position detecting system and device manufacturing method using the same	356/614
67	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5985495 A	19991116		Methods for measuring image-formation characteristics of a projection-optical system	430/22
68	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5968691 A	19991019		Method and apparatus for coating resist and developing the coated resist	430/30
69	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5962173 A	19991005		Method for measuring the effectiveness of optical proximity corrections	430/5
70	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5945239 A	19990831		Adjustment method for an optical projection system to change image distortion	430/30
71	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5936738 A	19990810		Focus monitor for alternating phase shifted masks	356/401

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
57	716/21		Kotani, Toshiya et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
58	250/548; 355/53; 355/67; 359/622; 430/30		Matsuura, Seiji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
59	355/55; 356/399		Suwa, Kyoidhi	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
60	257/E21.525; 700/30; 700/31		Pierrat, Christophe et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
61			Ausschnitt, Christopher P. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
62	356/401		Irie, Nobuyuki et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
63	430/22		Tokuda, Noriaki	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
64	355/53; 356/400		Taniguchi, Tetsuo et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
65	118/111; 118/232; 118/56; 118/58; 118/69		Yoshioka, Kazutoshi et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
66	250/548; 250/559.3; 356/401		Hasegawa, Masanobu et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
67	430/30		Okumura, Masahiko et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
68	430/311; 430/327; 430/330		Yoshioka, Kazutoshi et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
69	356/620; 430/22; 430/394		Leroux, Pierre et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
70			Taniguchi, Tetsuo	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
71	356/609; 356/613		Liebmann, Lars W. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR
72	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5916716 A	19990629		Emulation methodology for critical dimension control in E-Beam lithography	430/30
73	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5902703 A	19990511		Method for measuring dimensional anomalies in photolithographed integrated circuits using overlay metrology, and masks therefor	430/5
74	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5872618 A	19990216		Projection exposure apparatus	355/53
75	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5864433 A	19990126		Astigmatism-correcting optical system, projection exposure apparatus using the optical system and device manufacturing method	359/637
76	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5831715 A	19981103		Projection exposure apparatus with means to vary spherical aberration	355/53
77	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5825043 A	19981020		Focusing and tilting adjustment system for lithography aligner, manufacturing apparatus or inspection apparatus	250/548
78	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5805290 A	19980908		Method of optical metrology of unresolved pattern arrays	356/401
79	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5801954 A	19980901		Process for designing and checking a mask layout	716/21
80	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5793471 A	19980811		Projection exposure method and apparatus in which scanning exposure is performed in accordance with a shot layout of mask patterns	355/53
81	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5776645 A	19980707		Lithographic print bias/overlay target and applied metrology	430/22
82	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5756238 A	19980526		Lithographic print bias/overlay target and applied metrology	430/5
83	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5751428 A	19980512		Exposure method and exposure apparatus using the same	356/401
84	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5742376 A	19980421		Projection exposure apparatus and projection exposure method	355/53

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
72	430/296; 430/942		Butsch, Rainer et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
73	356/614; 430/22; 430/394		Leroux, Pierre et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
74	355/67; 355/71		Nagayama, Tadashi et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
75	250/548; 353/101; 355/71; 356/630; 359/822		Takahashi, Kazuhiro et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
76	355/52		Takahashi, Kazuhiro	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
77	355/55; 356/399		Suwa, Kyoichi	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
78			Ausschnitt, Christopher Perry et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
79	382/144; 430/5; 716/19		Le, Chin Aik et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
80	356/399		Kanda, Tsuneo et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
81	355/77; 356/400; 356/401; 430/30; 430/394; 430/5		Barr, Roger Lawrence et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
82	356/400; 356/401; 430/22; 430/30		Barr, Roger Lawrence et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
83	250/548; 250/559.3		Kataoka, Yoshiharu et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
84	355/50; 355/67; 355/71; 430/5		Makinouchi, Susumu	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>



	U	1	Document ID	Issue Date	Pages	Title	Current OR
85	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5684565 A	19971104		Pattern detecting method, pattern detecting apparatus, projection exposing apparatus using the same and exposure system	355/53
86	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5682323 A	19971028		System and method for performing optical proximity correction on macrocell libraries	716/19
87	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5677757 A	19971014		Projection exposure apparatus	355/71
88	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5677091 A	19971014		Lithographic print bias/overlay target and applied metrology	430/5
89	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5674650 A	19971007		Method of repetitively imaging a mask pattern on a substrate, and apparatus for performing the method	430/22
90	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5666205 A	19970909		Measuring method and exposure apparatus	356/401
91	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5654553 A	19970805		Projection exposure apparatus having an alignment sensor for aligning a mask image with a substrate	250/548
92	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5521036 A	19960528		Positioning method and apparatus	430/22
93	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5502311 A	19960326		Method of and apparatus for detecting plane position	250/548
94	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5496669 A	19960305		System for detecting a latent image using an alignment apparatus	430/22
95	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5486701 A	19960123		Method and apparatus for measuring reflectance in two wavelength bands to enable determination of thin film thickness	250/372
96	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5434026 A	19950718		Exposure condition measurement method	430/30
97	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5408083 A	19950418		Method of measuring the best focus position having a plurality of measuring mark images and a plurality of focus positions	250/201.2

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
85	250/548; 355/71; 356/400; 356/401		Oshida, Yoshitada et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
86	257/386; 257/390; 257/503; 700/186		Pasch, Nicholas et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
87	355/53		Taniguchi, Tetsuo et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
88	356/400; 356/401; 430/22; 430/30		Barr, Roger Lawrence et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
89	356/401; 430/394		Dirksen, Peter et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
90			Tateno, Hiroki et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
91	355/53; 356/400		Kawakubo, Masaharu et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
92	250/548; 356/400; 356/401; 430/312; 430/322; 430/5		Iwamoto, Yoshichika et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
93	250/557		Imai, Yuji et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
94	356/123; 356/394; 356/401; 430/30; 430/394		Pfarr, Rainer et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
95	356/632		Norton, Adam E. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
96	430/394; 430/396; 430/397		Takatsu, Norihiko et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
97	355/53		Hirukawa, Shigeru et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>

	U	1	Document ID	Issue Date	Pages	Title	Current OR
98	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5304441 A	19940419		Method of optimizing exposure of photoresist by patterning as a function of thermal modeling	430/30
99	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 5194893 A	19930316		Exposure method and projection exposure apparatus	355/53
100	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US RE33836 E	19920303		Apparatus and method for making large area electronic devices, such as flat panel displays and the like, using correlated, aligned dual optical systems	355/43
101	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4965630 A	19901023		Projection exposure apparatus	355/52
102	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4929083 A	19900529		Focus and overlay characterization and optimization for photolithographic exposure	356/400
103	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4908656 A	19900313		Method of dimension measurement for a pattern formed by exposure apparatus, and method for setting exposure conditions and for inspecting exposure precision	355/53
104	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4769680 A	19880906		Apparatus and method for making large area electronic devices, such as flat panel displays and the like, using correlated, aligned dual optical systems	355/43
105	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4759626 A	19880726		Determination of best focus for step and repeat projection aligners	356/124
106	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4644172 A	19870217		Electronic control of an automatic wafer inspection system	250/548
107	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4618938 A	19861021		Method and apparatus for automatic wafer inspection	382/148
108	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 4468565 A	19840828		Automatic focus and deflection correction in E-beam system using optical target height measurements	250/491.1

	Current XRef	Retrieval Classif	Inventor	S	C	P	2	3	4	5	Image Doc. Displayed	PT
98	430/296; 430/327; 430/328; 430/330; 430/394; 430/494; 430/942		Samuels, Donald J. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
99	355/55		Nishi, Kenji	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
100	355/46; 355/53		Resor, III, Griffith L. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
101	355/53		Kato, Kinya et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
102	356/123		Brunner, Timothy A.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
103	355/77; 356/401; 356/625		Suwa, Kyoichi et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
104	355/46; 355/53		Resor, III, Griffith L. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
105	356/125		Kroko, Catherine G.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
106	257/E21.53; 356/400		Sandland, Paul et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
107	348/126; 382/149; 716/19		Sandland, Paul et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>
108	219/121.26; 250/492.3		Blair, William W. et al.	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>	<input type="checkbox"/>		<input type="checkbox"/>